

03560.002760.



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shuichi YABU

Application No.: 09/811,447

Filed: March 20, 2001

For: EXPOSURE APPARATUS, GAS  
REPLACING METHOD, AND METHOD  
OF MANUFACTURING A  
SEMICONDUCTOR DEVICE

Examiner: A. Mathews

Group Art Unit: 2851

Allowed: February 28, 2003

Confirmation No.: 9561

May 28, 2003

TC 2800 MAIL ROOM

MAY 30 2003

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Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application  
as follows:

INTRODUCTORY COMMENTS

This Amendment has been prepared in accordance with the Revised Format established  
by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4,  
2003, and entitled "Amendments in a Revised Format Now Permitted."